

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

January 9, 2009

In re the application of:
Siddhartha Panda

Docket No. FIS920030133US1

Art Unit: 7420

Filed: 11/25/2003

Examiner: Lan Vinh

Application No.: 10/721,657

Confirmation No. 7420

For: Method Of Processing Wafers With
Resonant Heating

AMENDMENT AND/OR REPLY TO FINAL OFFICE ACTION
SUBMISSION UNDER 37 C.F.R. § 1.114 IN CONJUNCTION
WITH REQUEST FOR CONTINUED EXAMINATION

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action dated July 11, 2008 (the "Office Action"), please consider the following amendment and remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.